



AF/1765
IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **HATTORI, Kazuhiro**

Group Art Unit: **1765**

Serial No.: **09/816,784**

Examiner: **Lan Vinh**

Filed: **March 26, 2001**

P.T.O. Confirmation No.: **5542**

For: **DRY ETCHING METHOD, MICROFABRICATION PROCESS AND
DRY ETCHING MASK**

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

August 13, 2004

Sir:

In response to the Office Action dated **July 14, 2004**, please amend the above-identified application as follows:

The Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.